

**IN THE CLAIMS:**

**Please amend the claims as follows:**

Please now also cancel claims 10 and 11 without prejudice.

(All the pending claims are here under reproduced).

1. (Canceled)
2. (Previously amended) An in-situ plasma cleaning device for performing an atomic surface cleaning process to remove contaminants, comprising:
  - a cleaning assembly;
  - a magnetic field generator, located within the cleaning assembly, that generates a generally axially directed magnetic field to provide a plasma for cleaning a surface within the cleaning assembly;
  - wherein the cleaning assembly comprises a collector shield disposed opposite to the surface to be cleaned for collecting the contaminants and by-product material, wherein the cleaning assembly traverses the length of a target cylindrical surface and a substrate cylindrical surface during a cleaning process.
3. - 17. (Canceled)